FEB 0 1 2335

P/2699-26

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Toshikazu KITAJIMA et al.

Date

: February 1, 2005

Serial No.

10/624,871

Group Art Unit

: 2863

Filed

July 21, 2003

Examiner

: Xiuquin Sun

For

Confirmation No. :

7650

FILM THICKNESS MEASURING METHOD, RELATIVE

DIELECTRIC CONSTANT MEASURING METHOD, FILM THICKNESS MEASURING APPARATUS, AND RELATIVE DIELECTRIC CONSTANT MEASURING APPARATUS

via FACSIMILE - (703) 872-9306 Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

<u>AMENDMENT AFTER FINAL</u>

Sir:

This is a response to the Office Action mailed November 3, 2004 in the above-identified application. Reconsideration of the application is respectfully requested.

FEE CALCULATION

Any additional fee required has been calculated as follows:

If checked, "Small Entity" status is claimed.

NO. CLAIMS

HIGHESTNO.

AFTER AMENDMENT **PREVIOUSLY**

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PAID FOR	EXT	EXTRA PRESENT		RATE		FEE		
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4	** =	-0-		(\$100 SE or \$200)	\$	_0_	_	

FIRST PRESENTATION OF MULTIPLE DEPENDENT CLAIM (\$180 SE or \$360) * not less than 20

** not less than 3

TOTAL S -0-

ADDIT

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